

MicOS characterizes Ge-based micro-LEDs

Room-temperature Micro-electroluminescent Characterization of Ge-based IR Sources

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SPR IMAGING

Monolithic integration of optical components on CMOS platforms is ongoing in the optical communications industry. CMOS offers a mature and robust platform, and therefore is logical for building optical-interconnect modules. These modules include light sources, modulators, multiplexers, and detectors on a single substrate. Silicon is the foundational material for CMOS technology, but as a material with an indirect bandgap, it poses a serious obstacle to building light sources via CMOS-based integrated photonics.

There is particular interest in integrated sources from 1300–1600 nm. Germanium has a bandgap exactly within this range. Like Si, Ge is a group IV element, so it is a likely candidate for integration on a CMOS device. Yet Ge is also an indirect-bandgap material but with an adjacent (higher-energy) well in the conduction band capable of direct transitions. Various mechanisms have been developed to engineer population of this direct-bandgap path in SiGe alloys leading to integrated light sources^{1,2}.

One class of such SiGe light sources uses an electrical bias to populate the direct bandgap path. Electro-

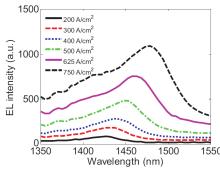


Fig. 1.
Electroluminescence spectra of a Si-Ge quantum well as a function of (left) bias current, and (right) temperature.

luminescence (EL) is an appealing method for characterizing such devices. Figs. 1 and 2 show the EL spectra of one such device (Fig. 3, left) measured using the HORIBA MicOS microscope spectrometer (Fig. 3, right).³

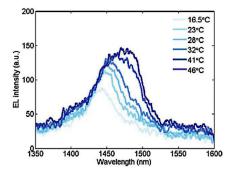


Fig. 2. Electroluminescence spectra of a Si-Ge quantum well as a function of temperature.

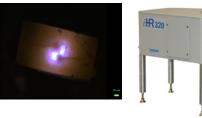


Fig. 3 (left). Representative image of EL from a micro-LED. (Right) Down-looking version of HORIBA MicOS with mapping stage.

References

- 1. S. Cho, et al., Optics Express, 20(14), 14921 (July 2012).
- 2. S. Chen, et al., Optics Express, 17(12), 10019 (June 2009).
- E. Fei, et al., Proc. IEEE Conf. on Group IV Photonics (2012), http://ieeexplore.ieee.org/xpl/abstractAuthors.jsp?reloa d=true&arnumber=6324112





Scientific



Specifications*

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Spectrometers		iHR320		iHR550
Spectral range ¹		200 nm to 1600 nm		
Spectral resolution ²		0.18 nm		0.1 nm
Detector	Туре	CCD 1024 × 256 OE ³	IGA 512 × 25	Single-channel
	Range	200-1050 nm	800–1600 nm	190-1600 nm ⁴
Excitation laser ⁵		532 nm	633 nm	785 nm
Microscope	Magnification	10×	50×	100×
Objective	Spot size	100 µm	<20 µm	<10 µm
Sample stage		xyz (manual or motorized)		

¹Depends on choice of objective, filters, and detectors.

*Specifications are subject to change without notice.

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ELEMENTAL ANALYSIS

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OPTICAL COMPONENTS

JOBIN YVON Technology

²For 1200 gr/mm grating and open-electrode CCD

³BIUV, BIVS, and BIDD formats available for specific quantum-efficiency requirements.

⁴Needs two detectors to cover entire range.

⁵Other options are available upon request.